

**INFORMATION DISCLOSURE CITATION**  
(Use several sheets if necessary)

Docket Number (Optional)  
END920030032US1 (16704)

Application Number  
10/665,993

Applicant(s)

Raminderpal Singh, et al.

Filing Date

Herewith

Group Art Unit

2826

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
VAMS		5,922,650	7/13/99	Ye			
		6,205,013B1	3/20/01	Gong et al.			
		2001/0040490A1	11/15/01	Tanaka			
		2002/0102835A1	8/1/02	Stucchi et al.			

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

VAMS		Silicon RF Technology-The Two Generic Approaches by Joachim N. Burghartz

EXAMINER

Victor A. Mondala Jr.

DATE CONSIDERED

4-18-05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.